



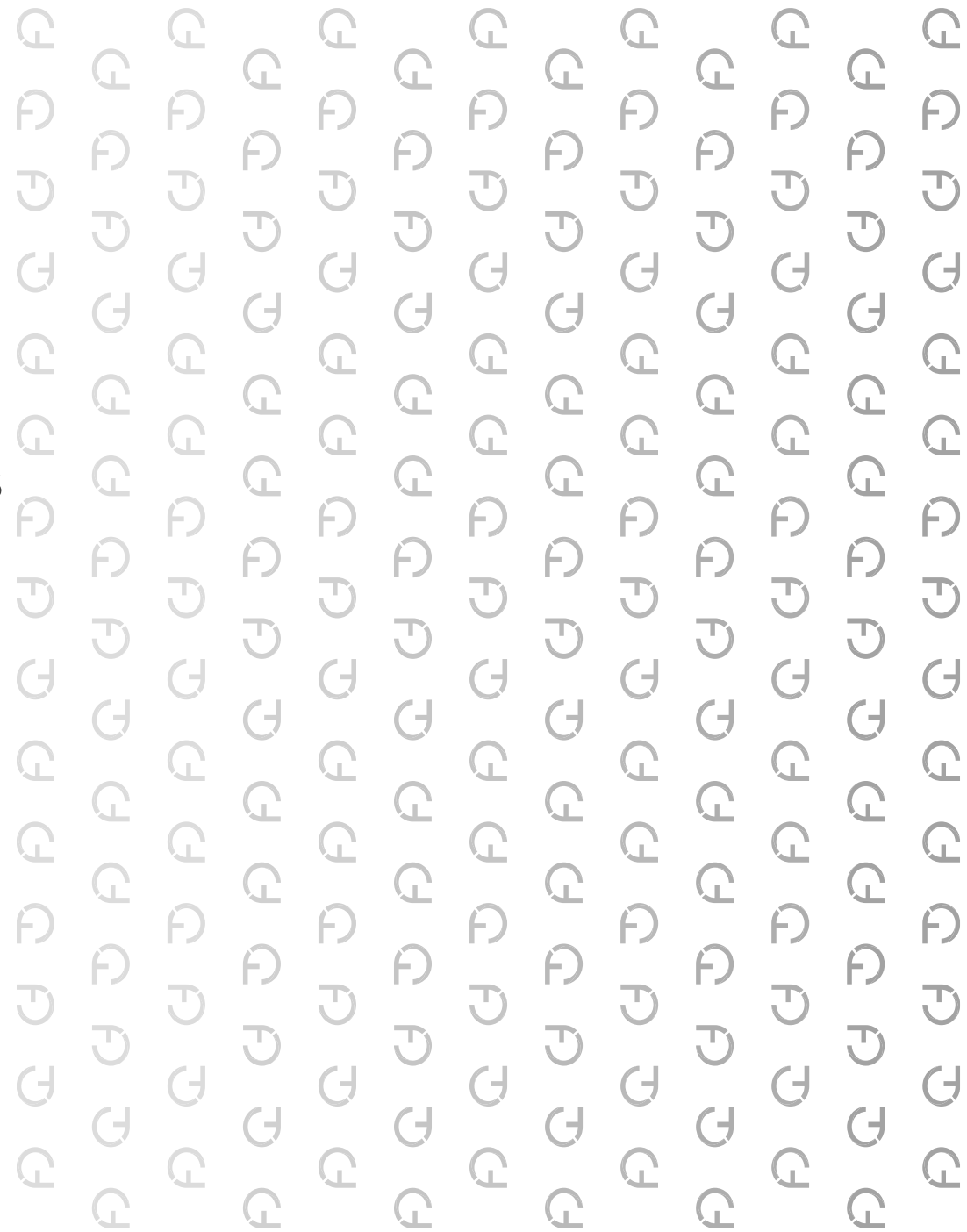
3D printing of Glass Micro-devices for Integrated Photonics and Miniaturized Optics

Dr. Rolando Ferrini



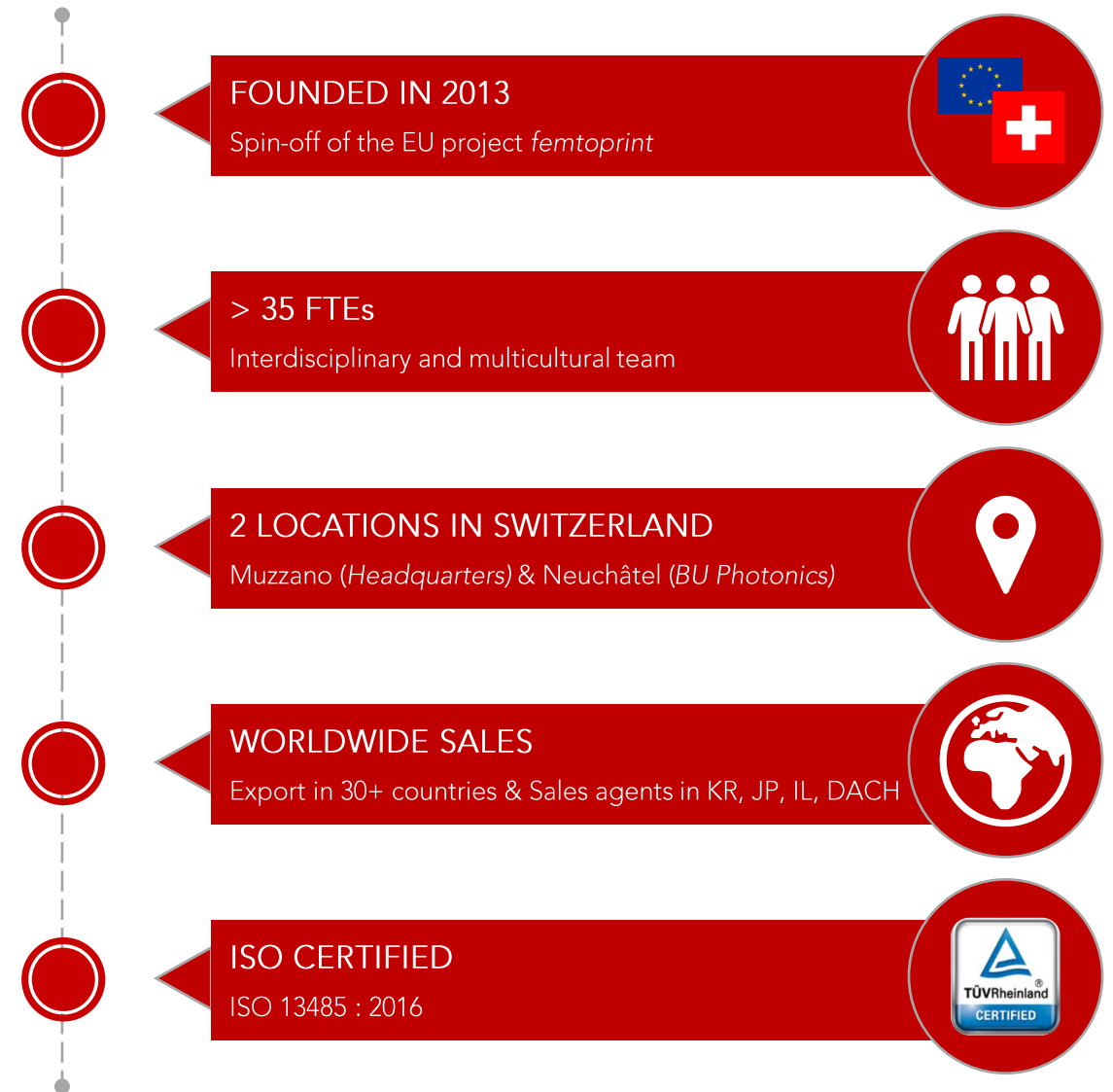
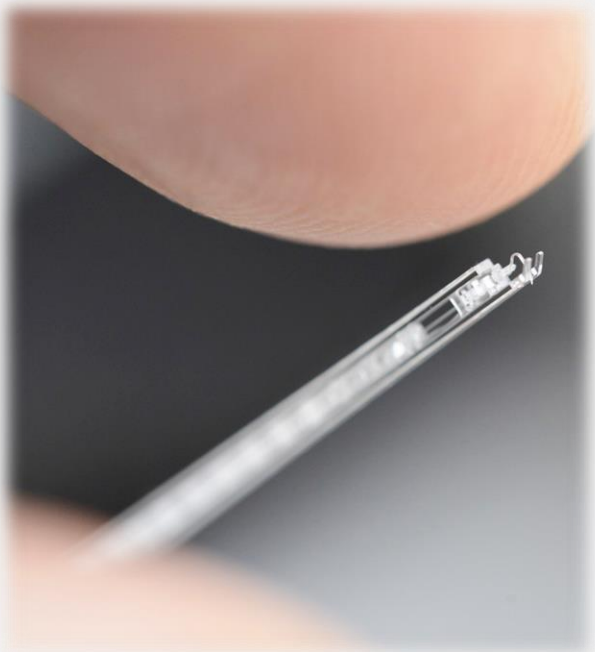
CMOS Compatible Integrated Photonics
IMEC – Leuven, September 7th-8th, 2022

FEMTOprint SA
Via Industria 3, 6933 Muzzano | Switzerland
www.femtoprint.ch | info@femtoprint.ch

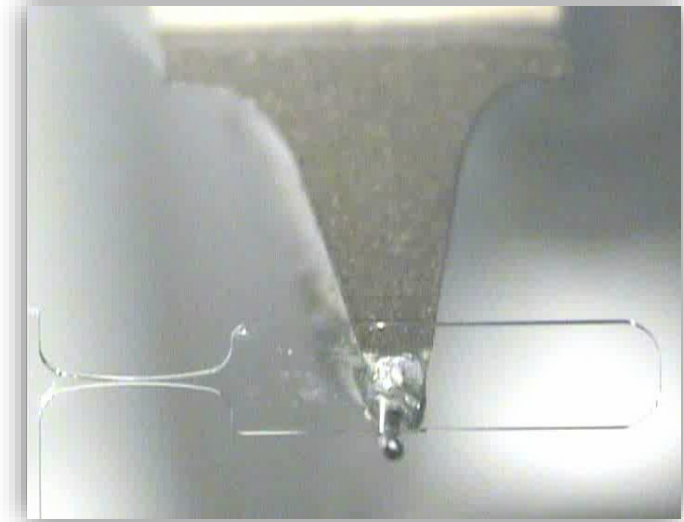


FEMTOprint IN A NUTSHELL

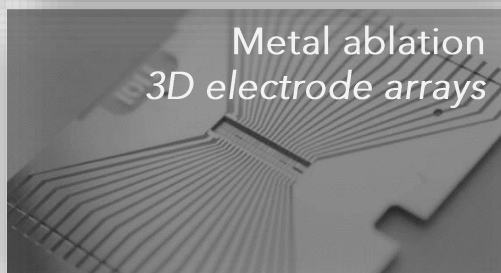
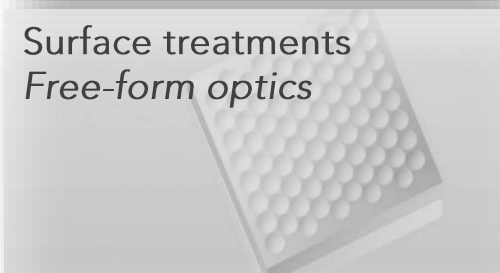
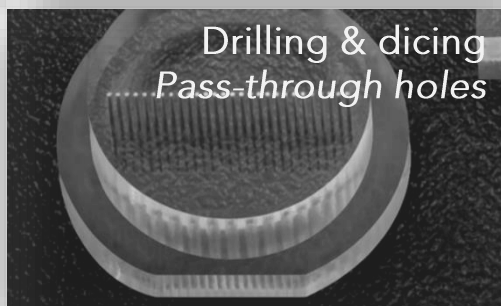
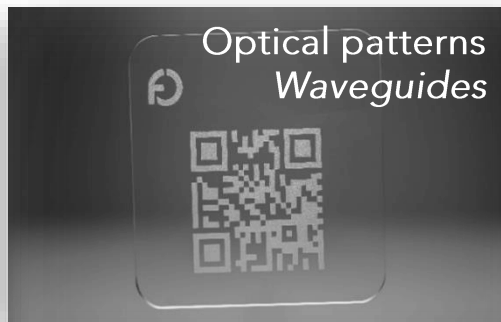
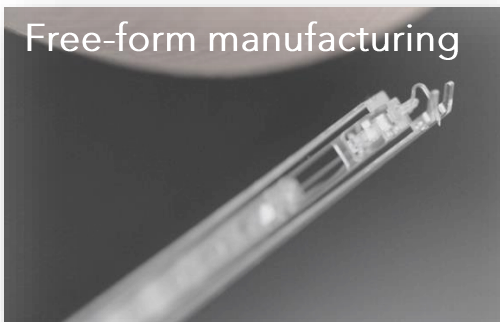
FEMTOprint is a Swiss high-tech **Contract Development & Manufacturing Organization (CDMO)** specialized in high-precision **3D microfabrication in glass**.



- 01 TRANSPARENT AND ISOTROPIC
- 02 STABLE AND ELECTRICALLY INSULATING
- 03 BIOCOMPATIBLE
- 04 ELEVATED THERMAL PROPERTIES
- 05 HIGHLY ELASTIC
- 06 RESISTANT TO CORROSION, ABRASION AND SCRATCHES
- 07 NEUTRAL TO MAGNETIC FIELDS



CAPABILITIES

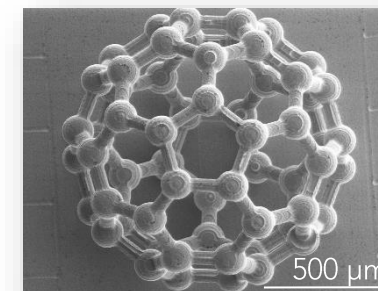


PERFORMANCES*

*in SiO₂

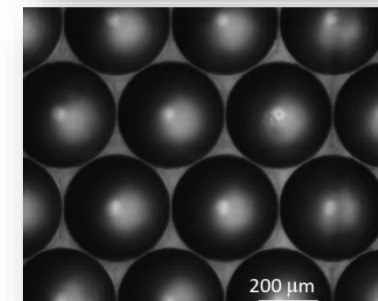
RESOLUTION AND TOLERANCES

- Process resolution ~ 1 μm
- XY tolerances +/- 1 μm
- Z tolerance +/- 2 μm



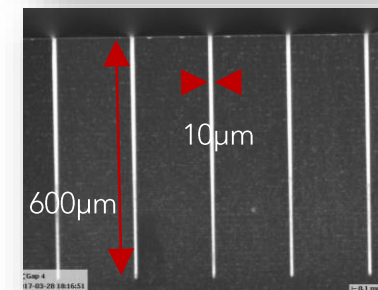
SURFACE QUALITY

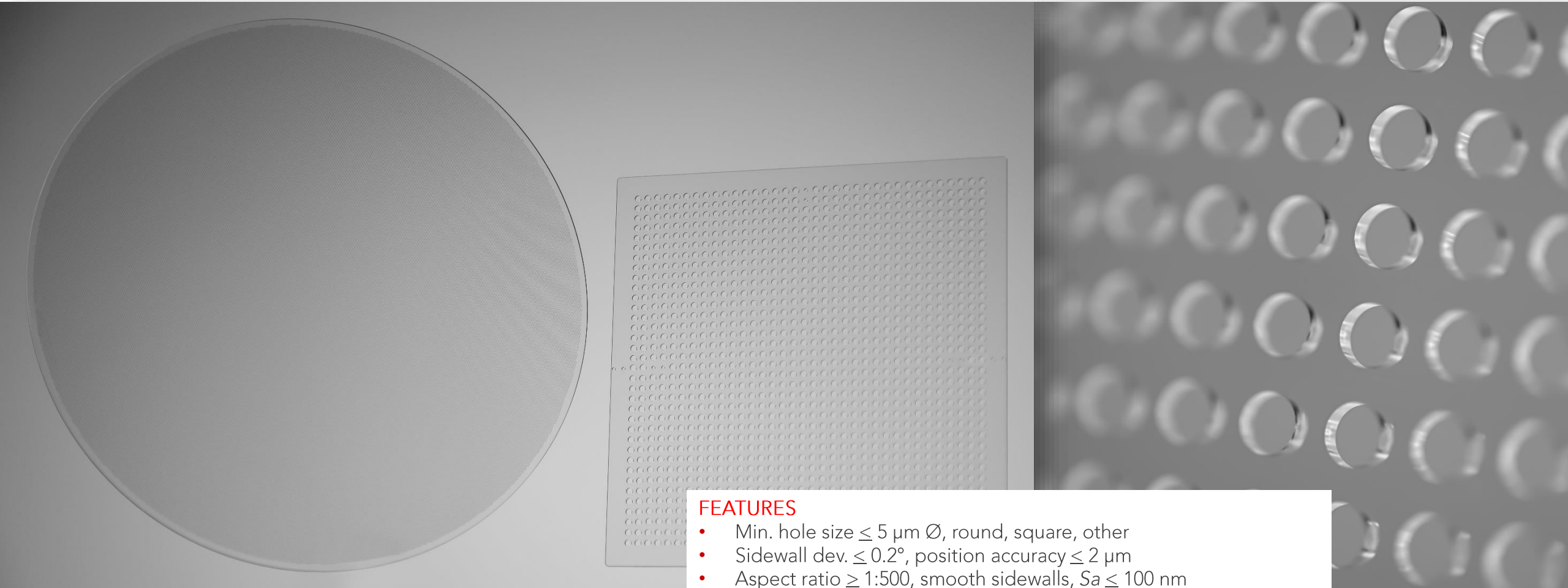
- Patterned surface $S_a \leq 100$ nm
- Surface treatment $S_a \leq 10$ nm



ASPECT RATIO

- Channel aspect ratio $\geq 1:500$
- Bulk height up to 30 mm
- Working area up to 300 mm Ø





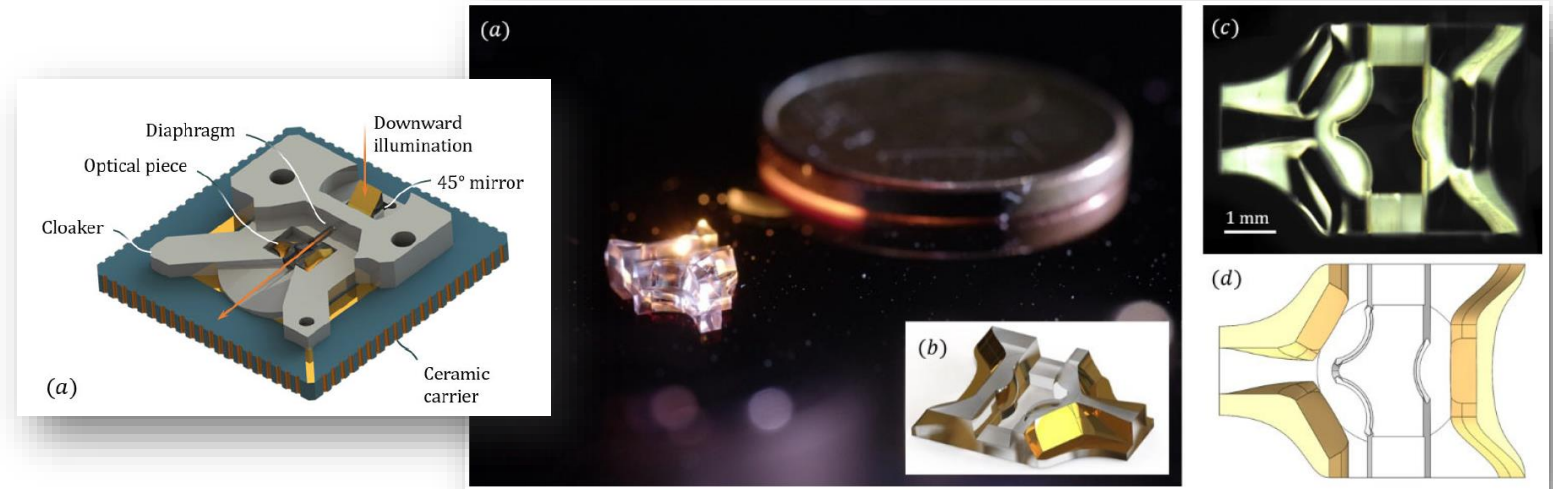
- FEATURES**
- Min. hole size $\leq 5 \mu\text{m } \varnothing$, round, square, other
 - Sidewall dev. $\leq 0.2^\circ$, position accuracy $\leq 2 \mu\text{m}$
 - Aspect ratio $\geq 1:500$, smooth sidewalls, $S_a \leq 100 \text{ nm}$
 - Sharp or tapered edge, no sagging and chipping

APPLICATION

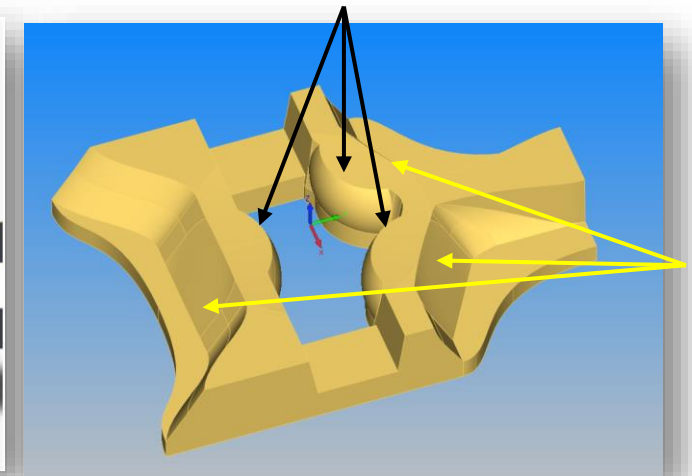
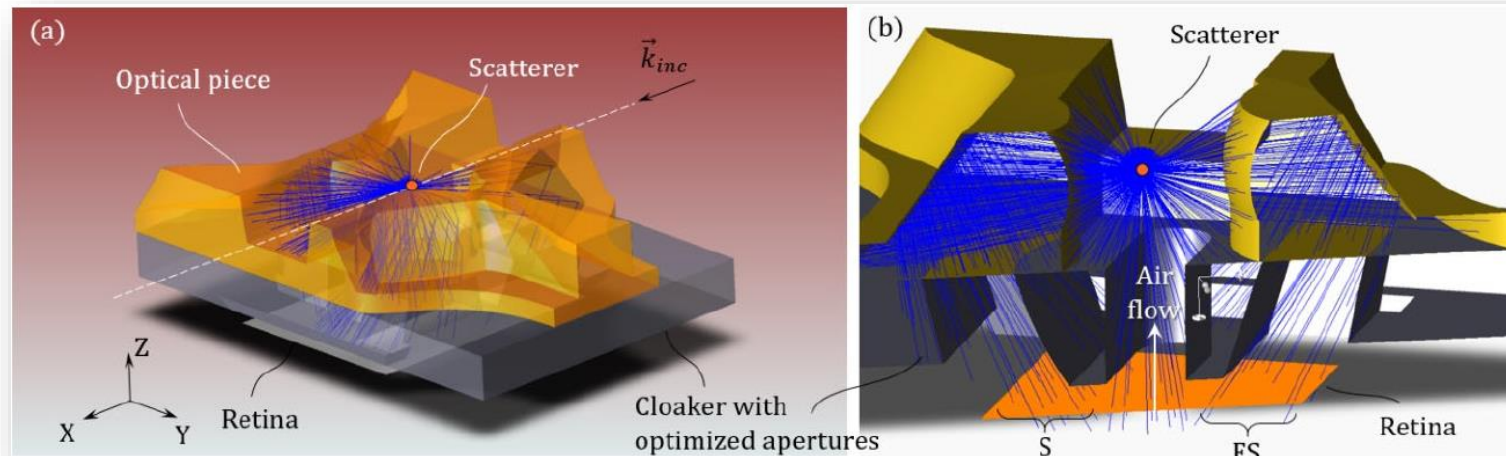
- Air quality monitoring
- Improved sensitivity by the integration of a miniaturized refractive/reflective optical system

USPs

- Monolithic integration of optical functions
- Free-form fabrication in 3D
- Co-packaged miniaturized optics



Slanted diopters

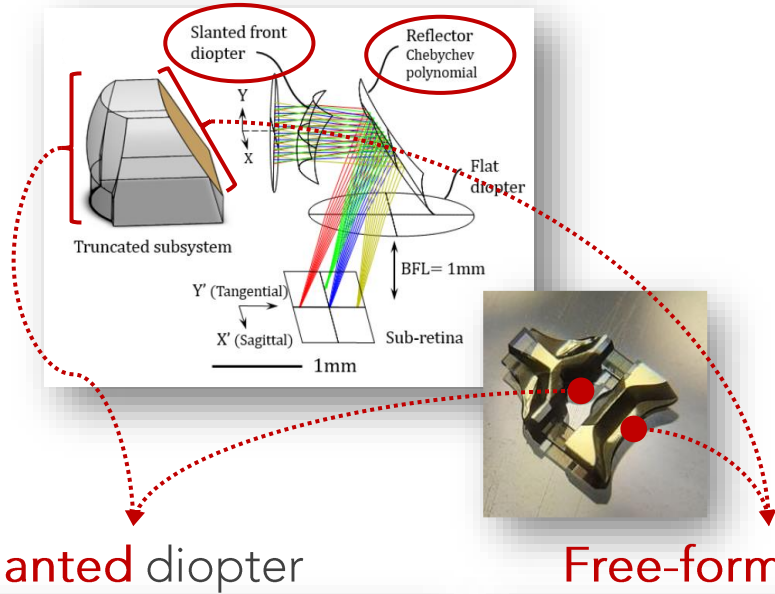


Free-form reflectors

CEA-LETI Minattec & Institut des Nanotechnologies de Lyon.

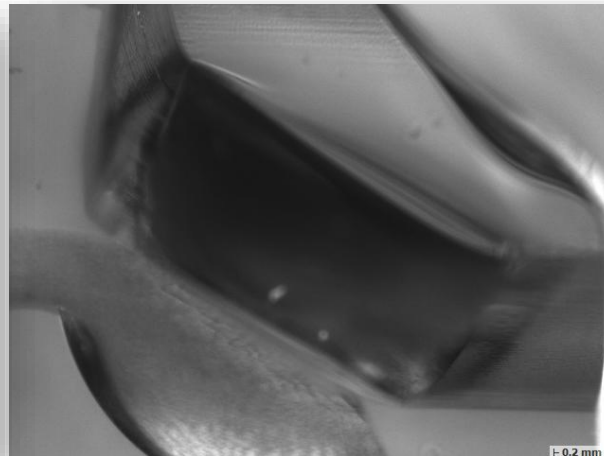
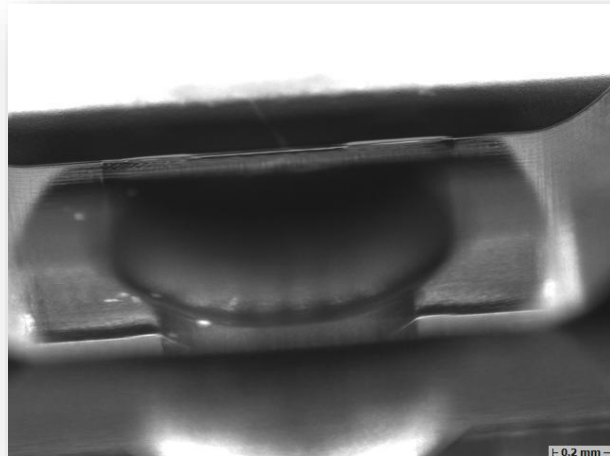
Jobert G. et al. Miniature Optical Particle Counter and Analyzer Involving a Fluidic-Optronic CMOS Chip Coupled with a Millimeter-Sized Glass Optical System. Sensors 2021, 21, 3181.

MINIATURIZED 3D OPTICAL SYSTEM

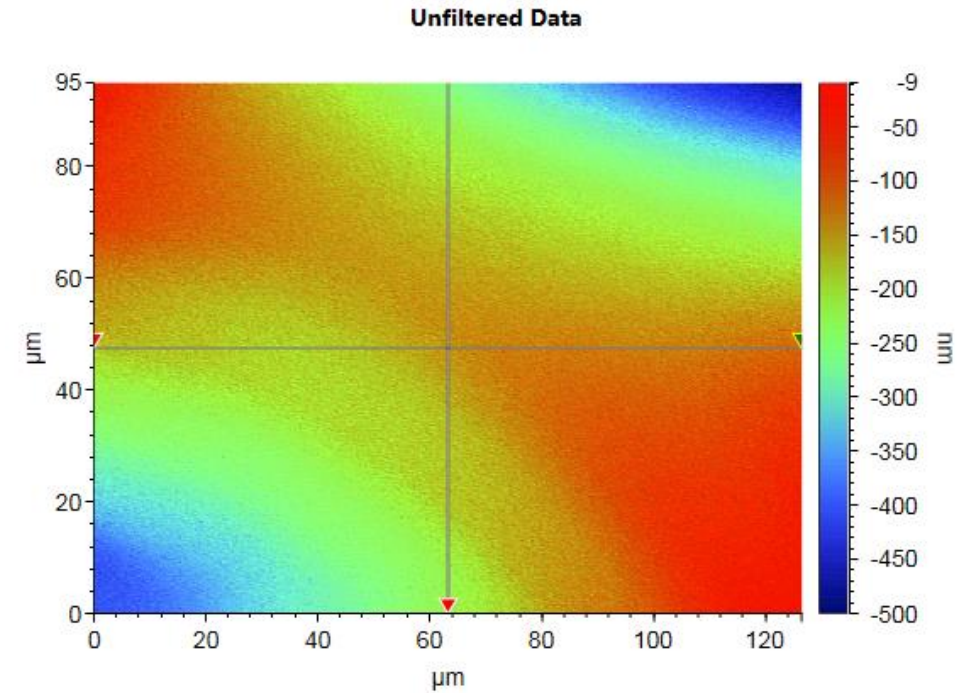


Slanted diopter

Free-form reflector



Interferometric image of the reflector surface

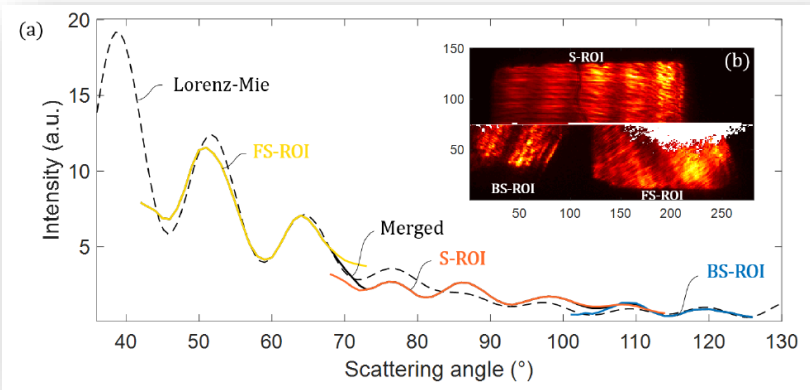


Surface roughness: $S_a = 6\text{nm}$

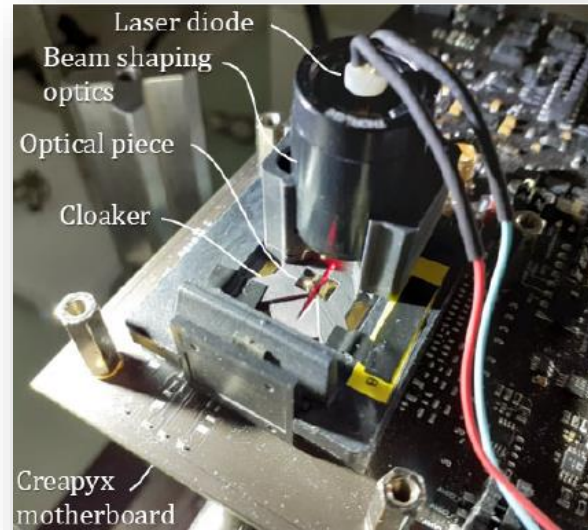
CEA-LETI Minatoc & Institut des Nanotechnologies de Lyon.

Jobert G. et al. Miniature Optical Particle Counter and Analyzer Involving a Fluidic-Optronic CMOS Chip Coupled with a Millimeter-Sized Glass Optical System. Sensors 2021, 21, 3181.

Functional Testing



Measured scattering signature reproduces well the theoretical model



Advantages

- Increased scattering flux collection
- Insensitivity to particle position
- Ultra-wide field of view
- Simplified image processing
- Real time monitoring
- Reduced costs
 - No reagents
 - No expensive instrumentation needed
 - Reusable several times

Possible future applications

- Identification of biochemicals
- Clinical diagnostics

CEA-LETI Minatec & Institut des Nanotechnologies de Lyon.

Jobert G. et al. Miniature Optical Particle Counter and Analyzer Involving a Fluidic-Optronic CMOS Chip Coupled with a Millimeter-Sized Glass Optical System. *Sensors* 2021, 21, 3181.

SPHERICAL or ASPHERICAL

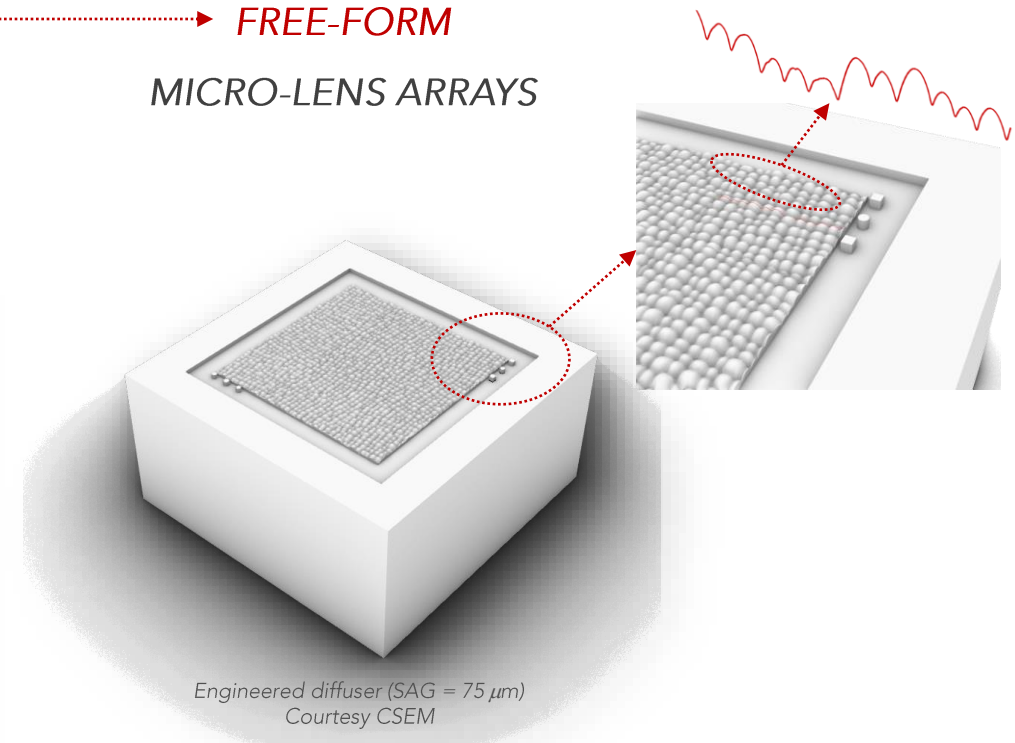
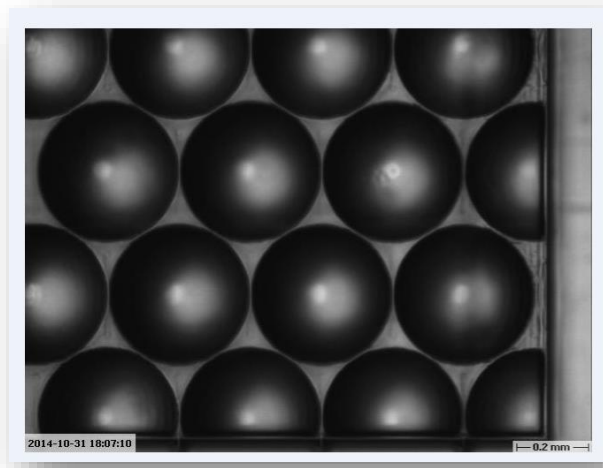
NON-SPHERICAL

FREE-FORM

MICRO-LENSES
&
MICRO-LENS ARRAYS

MICRO-OPTICAL ELEMENTS

MICRO-LENS ARRAYS



Feasibility

Fast prototyping

Pilot manufacturing

Small-to-medium
volume production

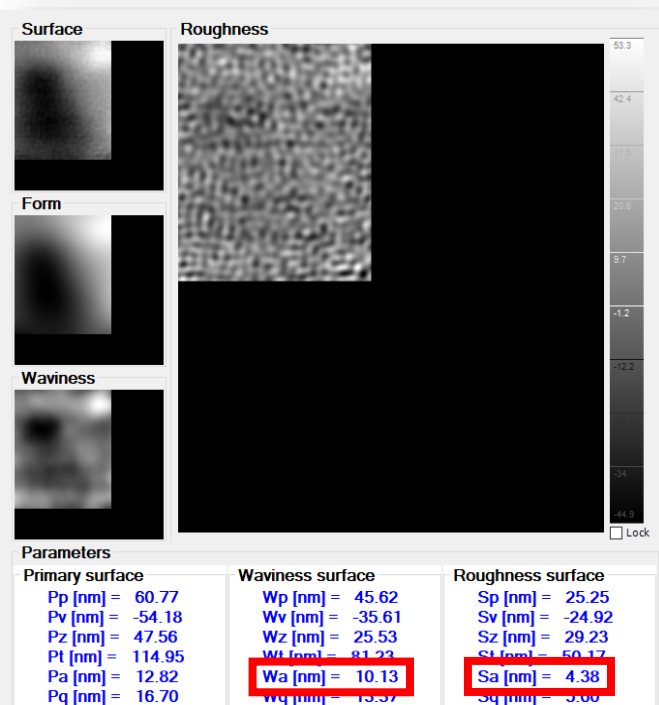
ORIGINATION
&
TOOLING

DEVELOPMENT: rapid cycles from concept to prototypes and small-to-medium product series

Enabling large volume production

Flat surfaces

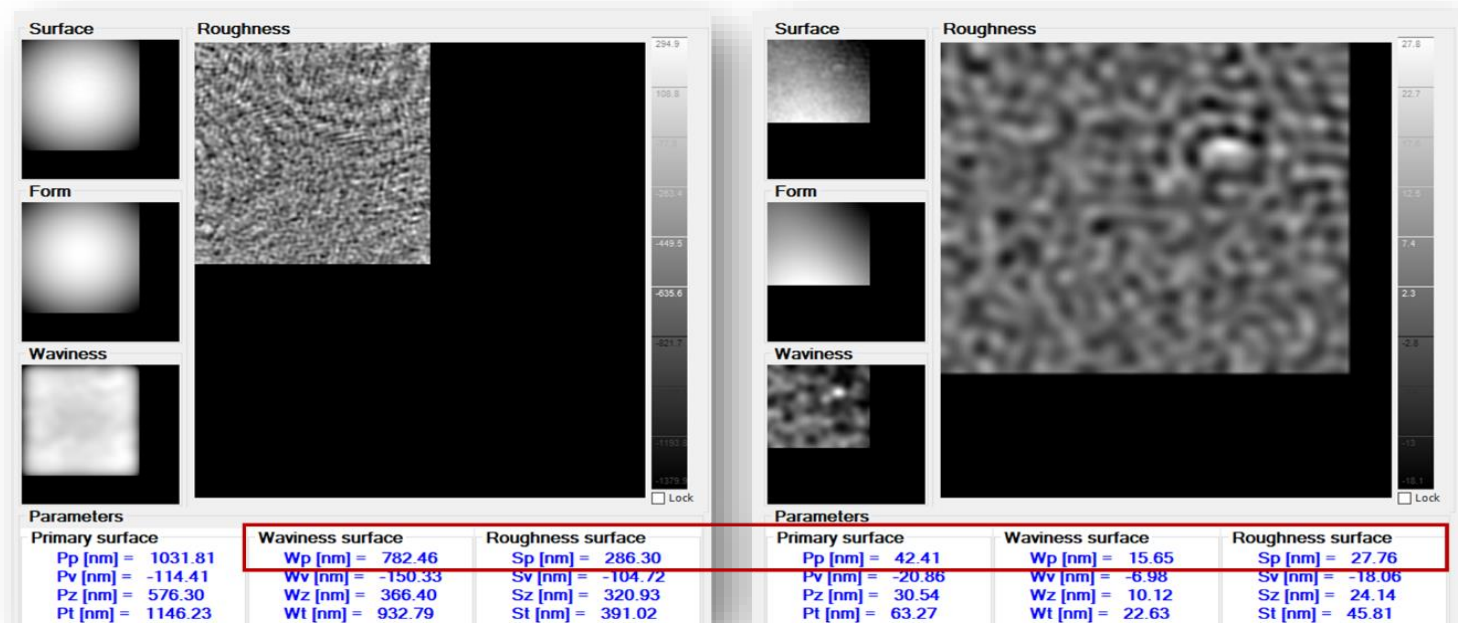
- $Sa < 10 \text{ nm}$



Spherical / Aspherical Micro-lenses

(RoC = 125 μm , SAG = 100 μm)

- $Sa \leq 10\text{-}20 \text{ nm}$
- Shape accuracy $\leq 1\text{-}3 \mu\text{m}$

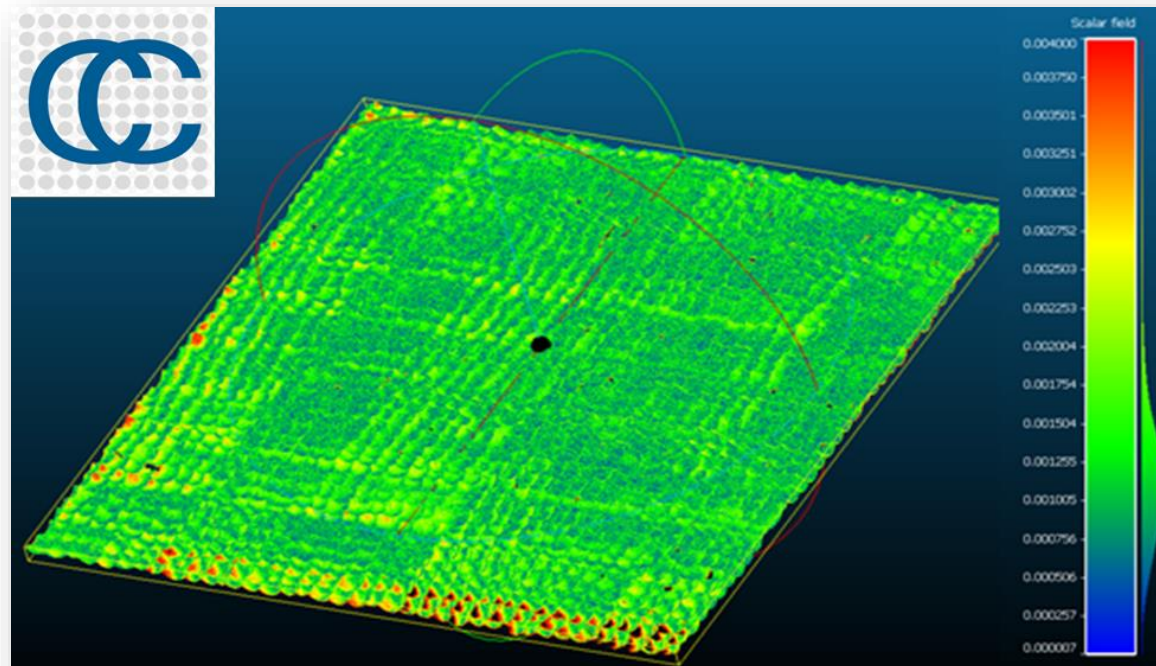


Innosuisse Project (n. 35418.1 IP-ENG)
Smart LAsER Manufacturing for precision industry 4.0 (SLAM 4.0)

Free-form Micro-lenses

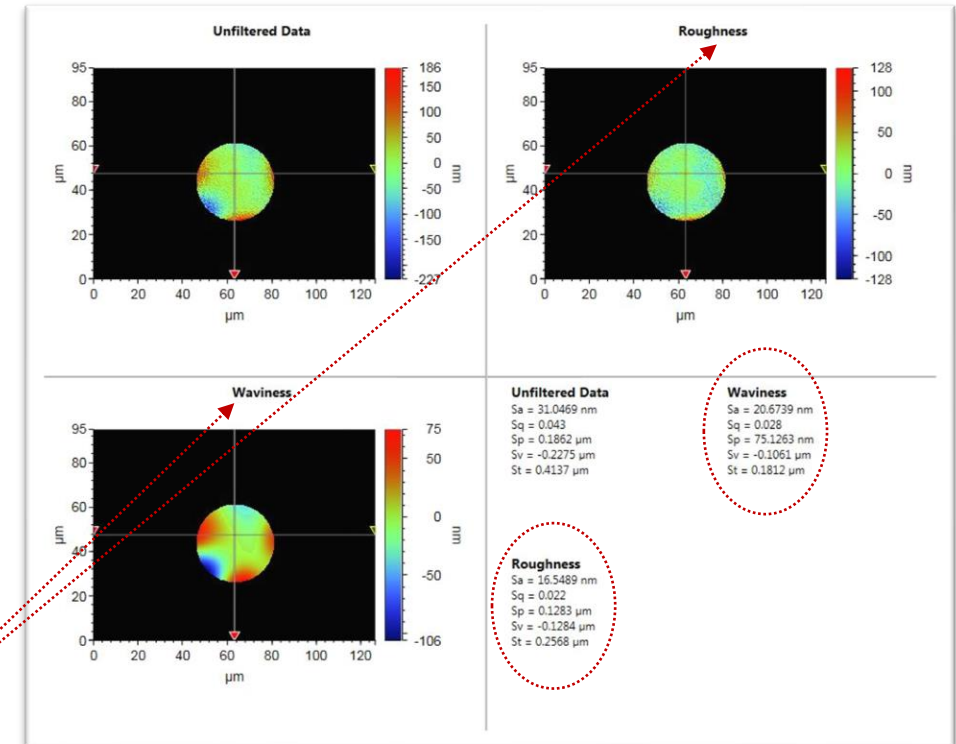
(SAG = 75 μm)

- $S_a \leq 20 \text{ nm}$
- Shape accuracy $\leq 2\text{-}3 \mu\text{m}$



Nominal design vs measured surface – Cloud Compare

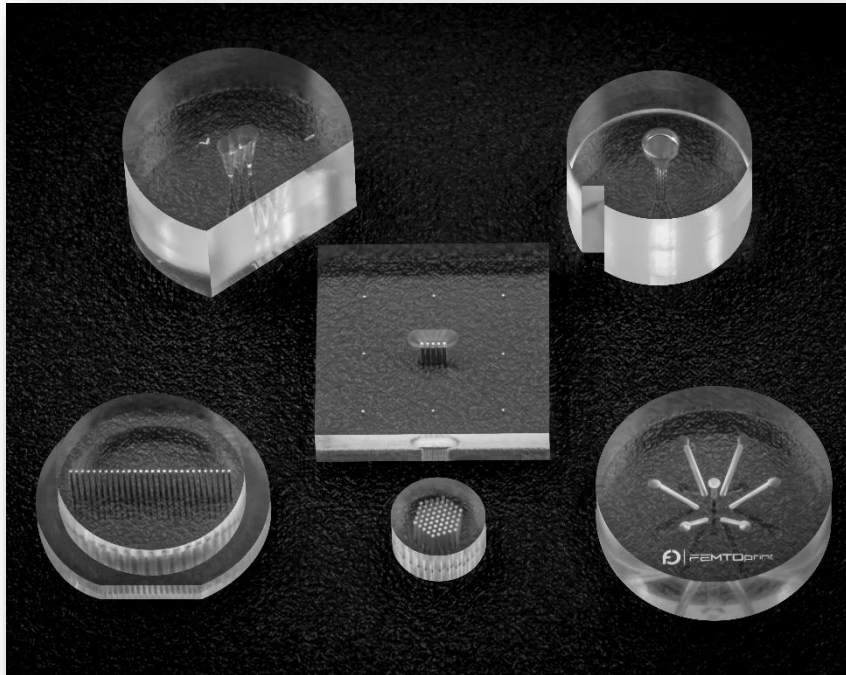
Courtesy of CSEM



Innosuisse Project (n. 35418.1 IP-ENG)
Smart LASer Manufacturing for precision industry 4.0 (SLAM 4.0)

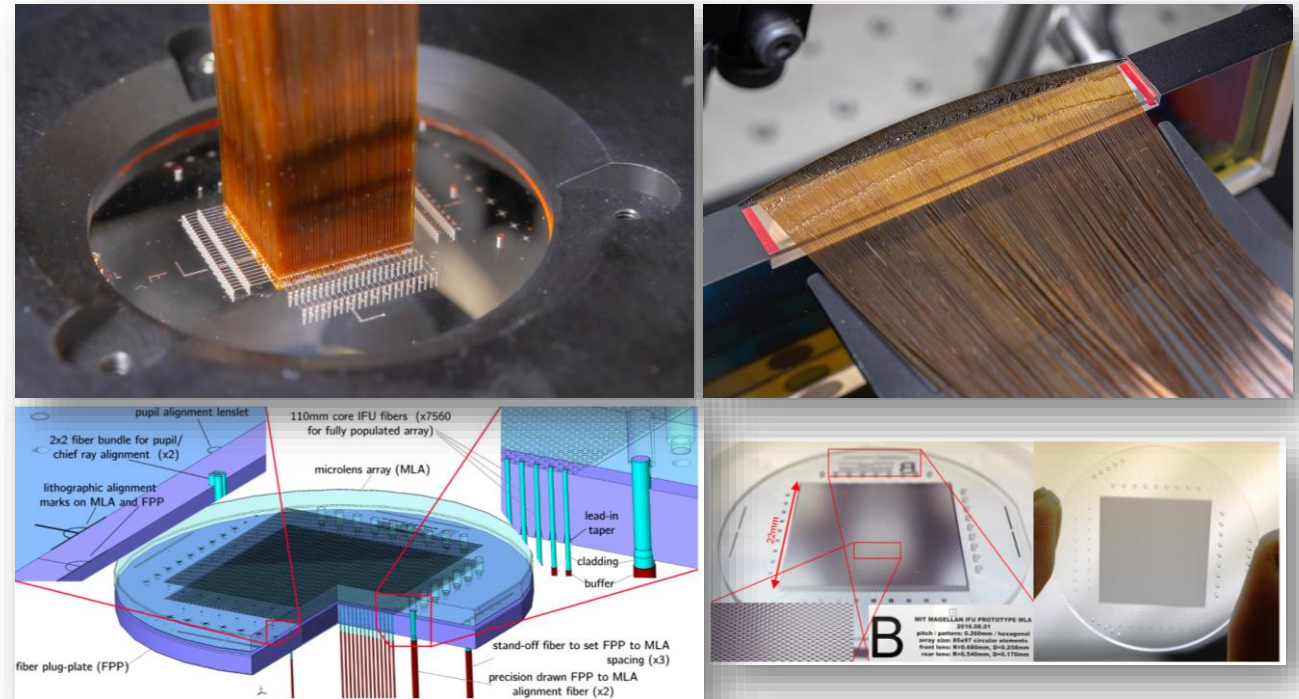
APPLICATION

- 2D fiber arrays & glass ferrules
- High precision fiber-to-chip alignment



APPLICATION

- Integral field spectrograph for astronomical telescope
- High precision 1D and 2D fibre arrays (2400-element) & MLA coupling



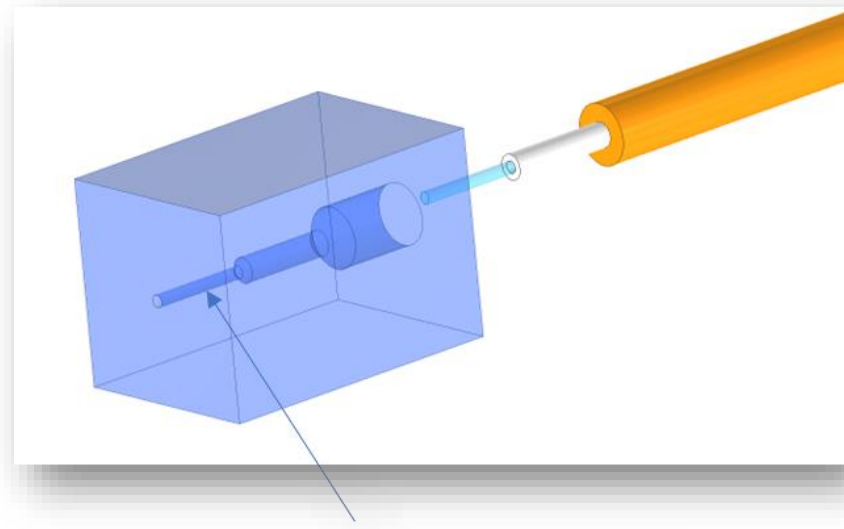
Courtesy of Gábor Fûrés, MIT Kavli Institute for Astrophysics and Space Research

USPs

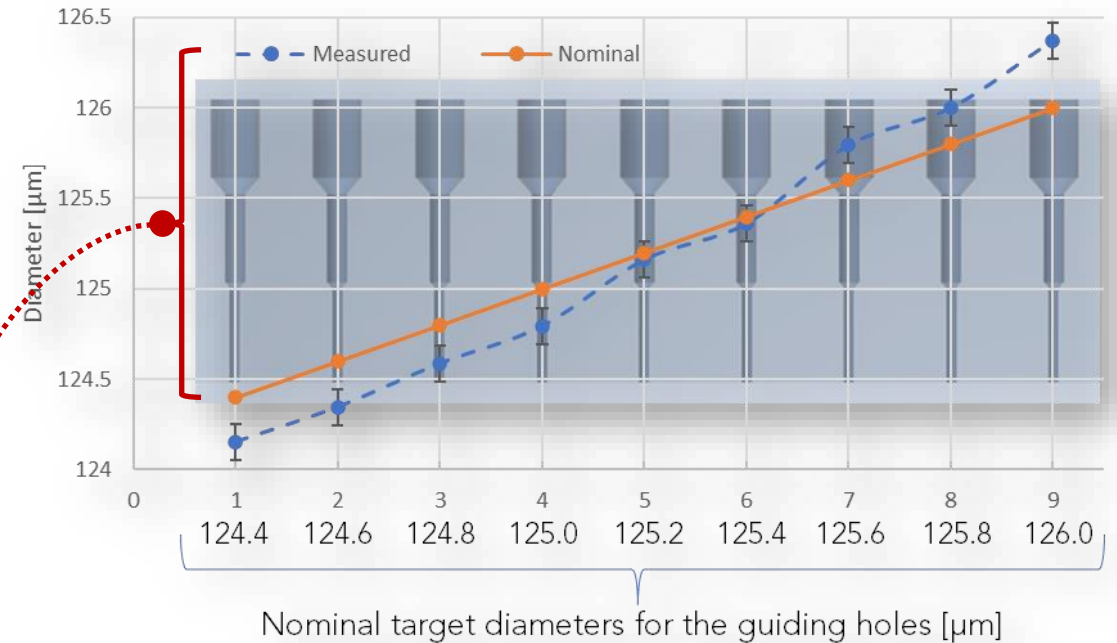
- Thin to thick glass ferrules: mechanical stability & flatness
- Customized hole arrays & additional assembly features
- Precision in hole diameter and positioning $< 1 \mu\text{m}$

FIBER FERRULES: SUB- μm CONTROL ON HOLE DIAMETER

- Fiber glass ferrules with varying nominal diameters of the guiding section (**steps = $0.2 \mu\text{m}$**)
- Mechanical measurements** of the effective diameter of the guiding section



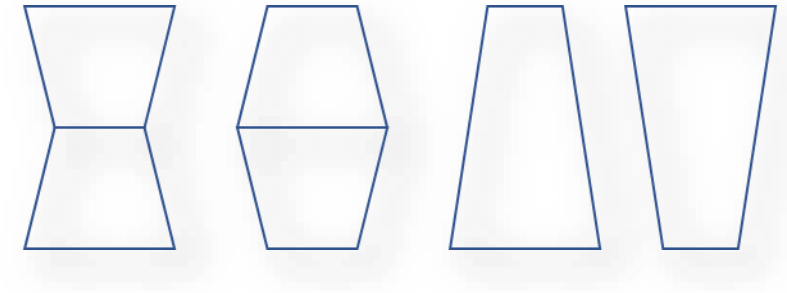
Guiding section (length > 1.5 mm)



The mechanical measurements confirm that

the diameters of the fabricated ferrules correspond to the nominal target values → sub- μm control

- Mechanical measurements → minimum diameter over the hole length
- The hole shape can vary



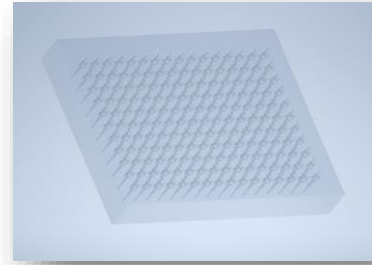
- **Optical measurements** to verify angular misalignment & conicity of the holes

The optical measurements did not reveal any diameter difference along single holes

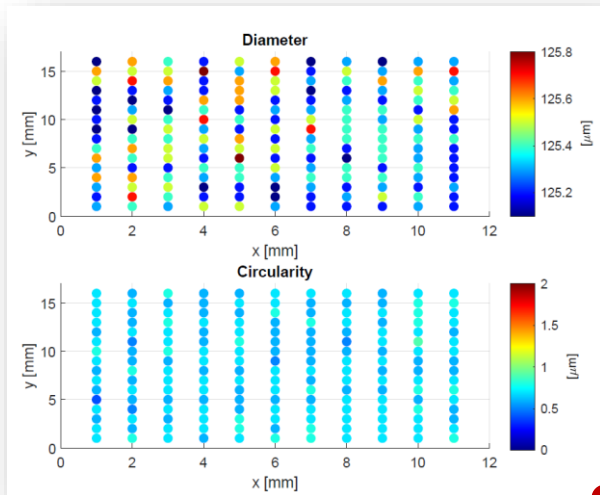
Error on hole cylindricity < 0.1°

FIBER FERRULES: REPEATABILITY

- 2D array of 11 x 16 holes
 - Target hole diameter = 125.5 μm
 - Inter-hole nominal distance (x,y) = 1 mm

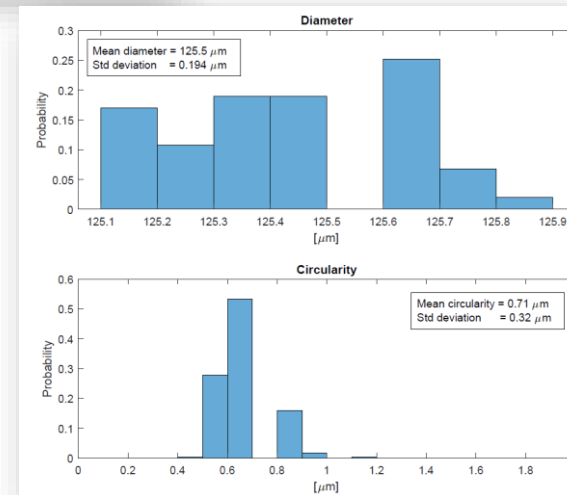


- 3x identical 2D arrays



- Diameter: narrow distribution around the target value
- Circularity: better than the microscope resolution ($\pm 2 \mu\text{m}$)

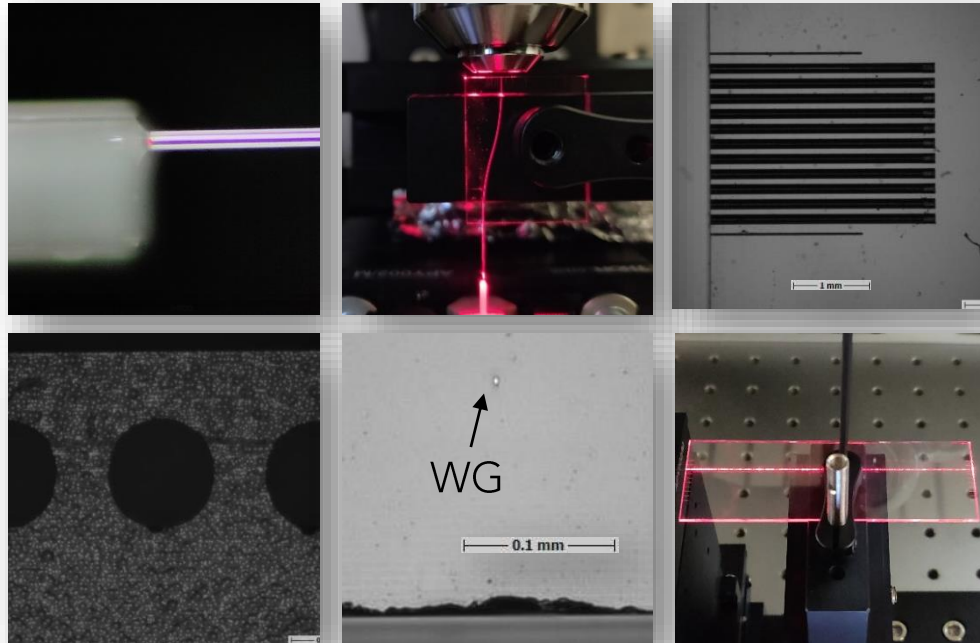
Hole homogeneity verified on a single array



- Average diameter on target
- Standard deviation $< 0.2 \mu\text{m}$
- Circularity better than the microscope resolution ($\pm 2 \mu\text{m}$)

Resolution of the diameter measurement = accuracy of the pin gauges, i.e. 0.1 μm

Repeatability verified on multiple arrays



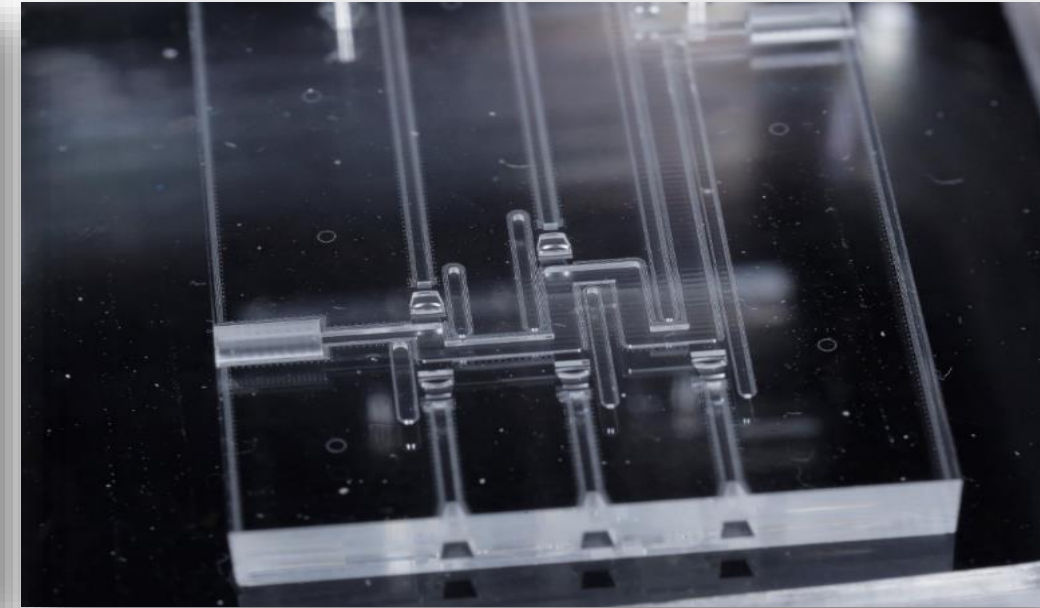
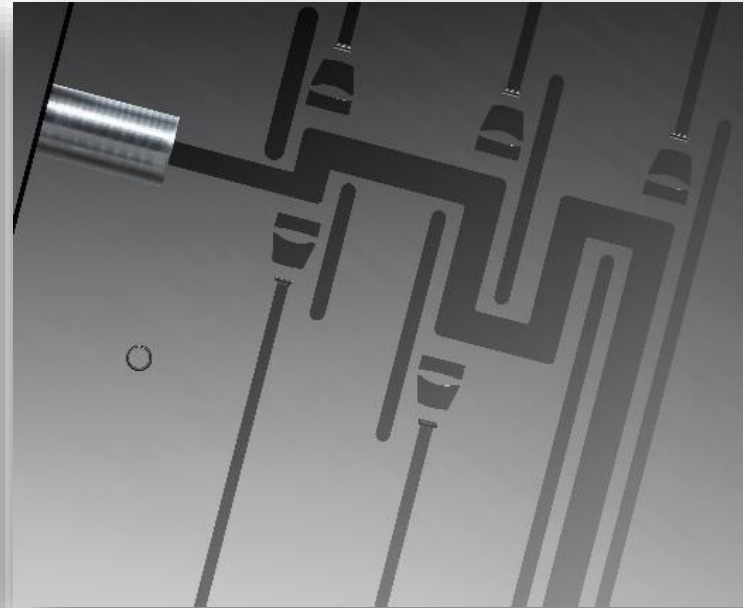
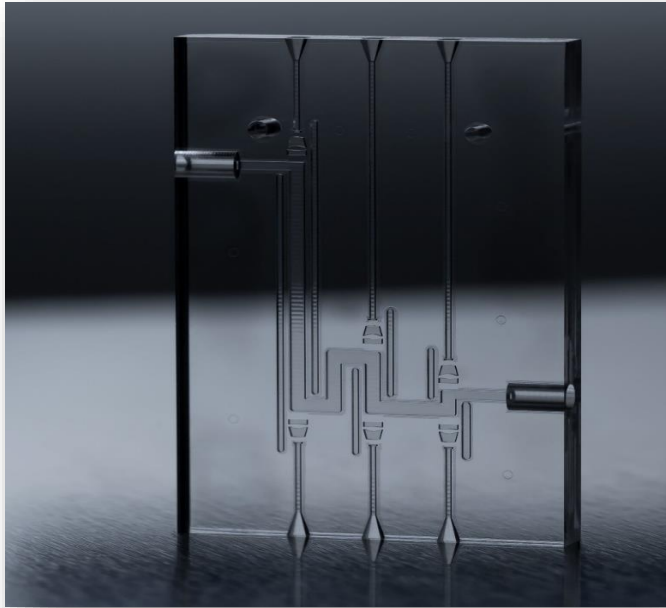
FEATURES

- Single mode & Multi-mode
- Bending in XYZ
- In-bulk termination possible
- Alignment markers and grooves can be conveniently added
- Facet polishing for rapid prototyping and characterization

| | |
|--------------------------|-------------------------|
| Materials | FS, BF33, EXG |
| Working λ [nm] | 630, 980, 1310, 1550 |
| MFD SM [μm] | 3 to 9 |
| Relative positioning | $< \pm 1 \mu\text{m}$ |
| Min. Bending Radius | $\approx 25 \text{ mm}$ |
| Propagation Loss | $< 0.7 \text{ dB/cm}$ |
| Δn | $10^{-2} - 10^{-3}$ |

USPs

- In-glass photonic wire-bonding
- Monolithic integration of functionalities
- Co-packaged photonic systems



APPLICATION

- Optofluidic Photonic Lab-on-a-Chip
- Monolithically integrated micro-optical system for the optical spectroscopy in a microfluidic structure

USPs

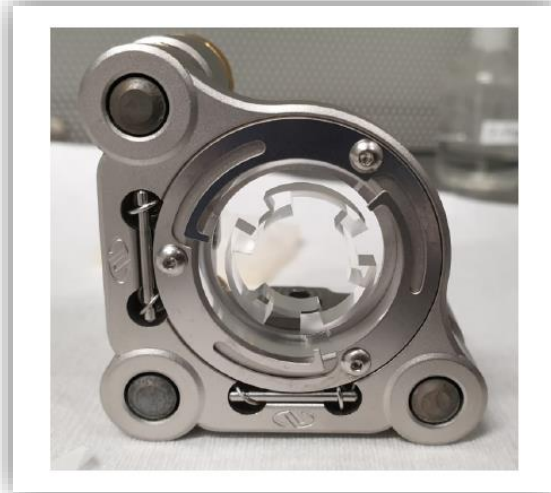
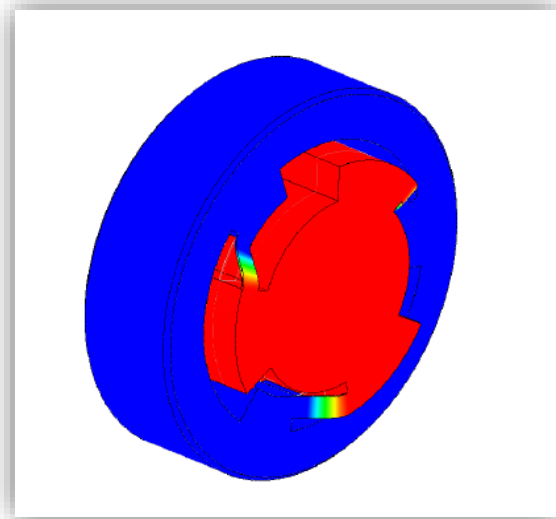
- Combination of optical & non-optical functionalities
- Monolithic integration
- Welding (glass-glass, glass-silicon, etc.)

CEA, DEN, DMRC, University of Montpellier, Marcoule, France.

Elodie Mattio et al. Photonic Lab-on-a-Chip analytical systems for nuclear applications: optical performance and UV-Vis-IR material characterization after chemical exposure and gamma irradiation. Journal of Radioanalytical and Nuclear Chemistry (2020) 323:965-973.

APPLICATION

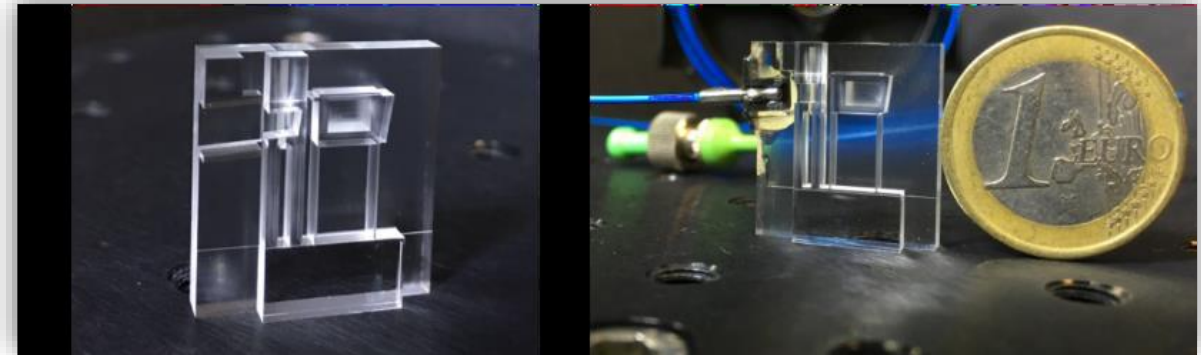
- Optomechanical inertial sensor
- Comparable performance to current sensors used in gravitational wave detectors



Jonathan Carter - A High Q, Quasi-Monolithic Optomechanical Inertial Sensor (2020)

APPLICATION

- Optomechanical accelerometer
- Tested for high sensitivity broadband acceleration measurements (mechanical oscillator quality factor $\approx 10^5$)



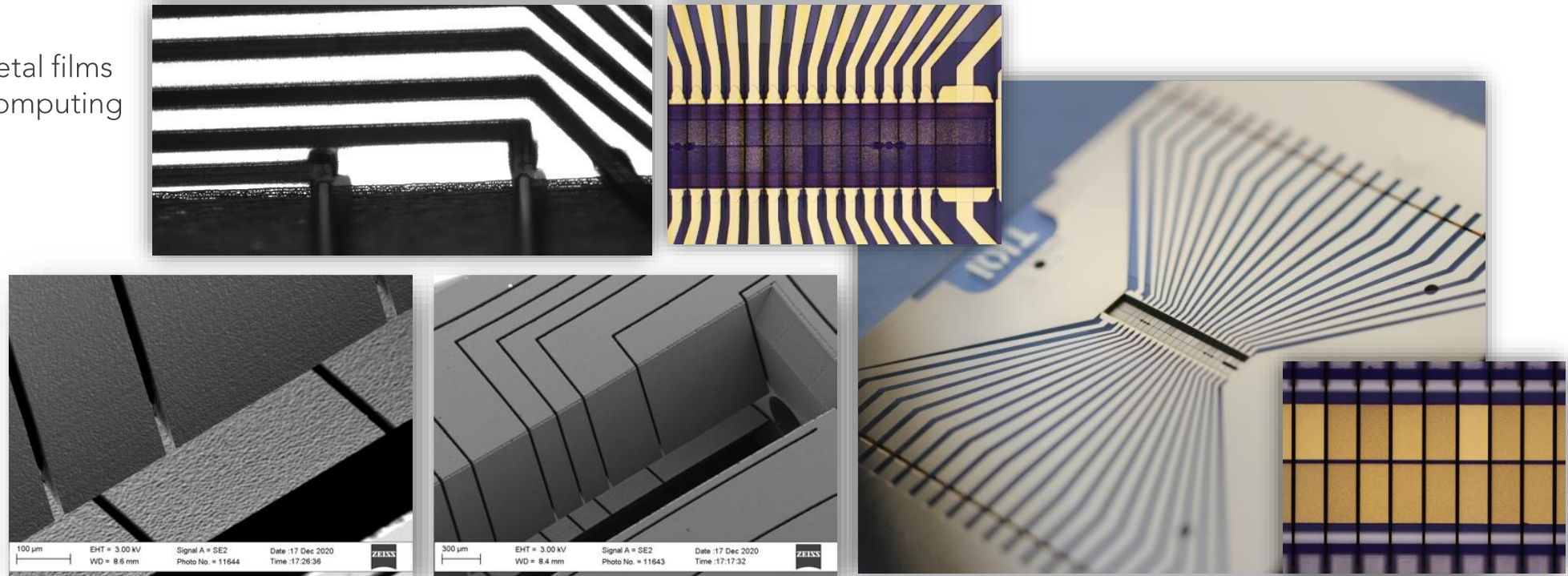
Felipe Guzmán - Compact fully monolithic optomechanical accelerometer (2018) / <https://lasso.engr.tamu.edu/>

USPs

- Exploitation the elastic properties of glass flexures
- Monolithic integration of functionalities
- Introduction of alignment features

APPLICATION

- Laser ablation of thin metal films
- Ion traps for quantum computing



Courtesy of ETH Zürich

USPs

- Laser ablation of different thin metallic layers: ITO, Cr-AU, Ti-Pt
- Electrode isolation on both flat & free-form surfaces (down to few μm 's)
- Integration of electrical functionalities

WHAT CAN WE DO FOR YOU?

- 3D printing of monolithically integrated glass micro-devices: from feasibility & fast prototyping to pilot & volume production
- Combine dedicated know-how in optics & photonics with full control over fabrication processes and production systems
- Provide solutions for integrated photonics, notably PICs:
 - Co-packaged miniaturized optics and micro-optics
 - In-glass photonic wire-bonding
 - High precision 1D & 2D fiber arrays (e.g. for passive alignment)
 - Packaging & assembly (incl. welding)
 - Integration of mechanical & electrical functionalities

WHAT CAN YOU DO FOR US?

- Design, Metrology, Functional testing (currently)
- Requests for fast-prototyping, pilot manufacturing, and mastering/tooling services
- Collaboration on the development & manufacturing of
 - miniaturized & micro- optical components, devices, and systems
 - application specific photonic systems
 - multifunctional glass micro-systems

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